

FORM PTO-1449 (Modified)  
U.S. Department of Commerce, Patent and Trademark Office

Docket No.

01-212/1P

Serial No.

10/6/4776

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicants

Wilbur G. Catabay et al.

Filing Date  
Herewith 7/7/03Group  
Unknown 2813

## U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
OS	AA	5,874,367	2/23/99	Dobson	438	787	—
	AB	6,028,015	2/22/00	Wang et al.	438	789	3/29/99
	AC	6,114,259	9/5/00	Sukharev et al.	438	789	7/27/99
	AD	6,147,012	11/14/00	Sukharev et al.	438	787	11/12/99
	AE	6,204,192	3/20/01	Zhao et al.	438	723	3/29/99
	AF	6,232,658	5/15/01	Catabay et al.	257	701	6/30/99
	AG	5,314,845	5/24/94	Lee et al.	437	238	2/2/90
	AH	5,915,203	6/22/99	Sengupta et al.	438	669	6/10/97
	AI	6,395,607	5/28/02	Chung	438	312	6/9/99
	AJ						
	AK						

## Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

OS	AR	Bothra, S., et al., "Integration of 0.25 $\mu$ m Three and Five Level Interconnect System for High Performance ASIC", 1997 Proceedings Fourteenth International VMIC Conference, Santa Clara, CA, June 10-12, 1997, pp.43-48.
	AS	Dobson, C.D., et al., "Advanced SiO <sub>2</sub> Planarization Using Silane and H <sub>2</sub> O <sub>2</sub> ", Semiconductor International, December 1994, pp. 85-88.
	AT	McClatchie, S., et al., "Low Dielectric Constant Oxide Films Deposited Using CVD Techniques", 1998 Proceedings Fourth International DUMIC Conference, February 16-17, 1998, pp. 311-318.

Examiner

Date Considered

12/6/04

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DS	BA	6,221,775	4/24/01	Ference et al.	438	691	9/24/98
	BB	5,854,126	12/98	Tobben et al.	438	626	
	BC	6,207,570	3/01	Mucha	438	692	
	BD	5,989,998	11/23/99	Sugahara et al.			
	BE	6,054,379	4/25/00	Yau			
	BF	6,215,087	4/10/01	Akahori et al.			
	BG	5,930,655	7/27/99	Cooney, III			
	BH	6,043,145	3/28/00	Suzuki et al.			
	BI	6,063,702	5/16/00	Chung			
	BJ	6,403,466	6/02	Loqatin	438	627	
	BK	6,447,668	9/02	Wang	205	645	

## Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	BL							
	BM							
	BN							
	BO							
	BP							

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

DS	BR	Peters, Laura, "Low-k Dielectrics: Will Spin-On or CVD Prevail?", <u>Semiconductor International</u> , Vol. 23, No. 6, June, 2000, pp. 108-110, 114, 116, 118, 122, and 124.
↓	BS	Peters, Laura, "Pursuing the Perfect Low-k Dielectric", <u>Semiconductor International</u> , Vol. 21, No. 10, September, 1998, pp. 64-66, 68, 70, 72, and 74.
	BT	

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DS	CA	5,904,154	5/18/99	Chien et al.	134	1.2	7/24/97
	CB	5,882,489	3/16/99	Bersin et al.	204	192.35	4/26/96
	CC	5,858,879	1/12/99	Chao et al.	438	725	6/6/97
	CD	3,012,861	12/12/61	Ling	23	223.5	1/15/60
	CE	3,178,392	4/13/65	Kriner	260	46.5	4/9/62
	CF	3,832,202	8/27/74	Ritchie	106	287	8/8/72
	CG	3,920,865	11/18/75	Läufer et al.	427	220	4/6/72
	CH	4,705,725	11/10/87	Glajch et al.	428	405	11/28/86
	CI	5,194,333	3/16/93	Ohnaka et al.	428	405	12/18/90
	CJ	5,874,745	2/23/99	Kuo	257	59	8/5/97
	CK	6,440,295	8/02	Wang	205	640	—

## Foreign Patent Documents

## Translation

		Document Number	Date	Country	Class	Subclass	Yes	No
DS	CL	DE 198 04 375 A1	7/1/99	Germany	H 01 L	21/312		X
	CM	EP 0 706 216 A2	4/10/96	Europe	H 01 L	23/532	N/A	
	CN	EP 0 949 663 A2	10/13/99	Europe	H 01 L	21/312	N/A	
	CO	63003437	1/8/88	Japan	H 01 L	21/90	X-Abstract Only	
	CP	WO 99/41423	8/19/99	PCT	C 23 C		N/A	

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	CR	
	CS	
	CT	

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DS	DA	6,066,574	5,23/00	You et al.	438	781	11/6/98
	DB	6,051,477	4/18/00	Nam	438	404	10/22/96
	DC	6,025,263	2/15/00	Tsai et al.	438	624	9/11/97
	DD	5,939,763	8/17/99	Hao et al.	257	411	9/5/96
	DE	5,864,172	1/26/99	Kapoor et al.	257	634	8/13/96
	DF	5,688,724	11/18/97	Yoon et al.	437	235	12/23/94
	DG	5,470,801	11/28/95	Kapoor et al.	437	238	6/28/93
	DH	5,364,800	11/15/94	Joyner	437	28	6/24/93
	DI	4,771,328	9/13/88	Malaviya et al.	357	49	11/24/86
	DJ	3,652,331	3/28/72	Yamazaki	117	201	3/13/69
	DK						

Foreign Patent Documents

Translation

		Document Number	Date	Country	Class	Subclass	Yes	No
	DL							
	DM							
	DN							
	DO							
	DP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

DR	Koda, Seiichiro, et al., "A Study of Inhibition Effects for Silane Combustion by Additive Gases", <u>Combustion and Flame</u> , Vol. 73, No. 2, August, 1988, pp. 187-194.
DS	Sugahara, Satoshi, et al., "Chemical Vapor Deposition of CF <sub>3</sub> -Incorporated Silica Films for Interlayer Dielectric Application", 1999 Joint International Meeting, <u>Electrochemical Society Meeting Abstracts</u> , Vol. 99-2, 1999, Abstract No. 746.
DT	

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DS	EA	5,628,871	5/13/97	Shinagawa	438	514	6/24/94
	EB	6,153,524	11/28/00	Henley et al.	438	691	7/28/98
	EC	6,051,073	4/18/00	Chu et al.	118	723	6/3/98
	ED	5,580,429	12/3/96	Chan et al.	204	192.38	6/7/95
	EE	5,558,718	9/24/96	Leung	118	723E	4/8/94
	EF	6,037,248	3/14/00	Ahn	438	619	6/13/97
	EG	5,675,187	10/7/97	Numata et al.	257	758	5/16/96
	EH	5,559,367	9/24/96	Cohen et al.	257	77	7/12/94
	EI	5,376,595	12/27/94	Zupancic et al.	501	12	8/28/92
	EJ	6,043,167	3/28/2000	Lee et al.	438	789	10/10/97
	EK						

## Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
DS	EL	2000-267128	9/29/00	Japan	G02F	1/136	X-Abstract Only	
	EM							
	EN							
	EO							
	EP							

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	ES	
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